## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

**In re Application of:** Nathan R. Brown

Serial No.: 10/715,267

Filed: November 17, 2003

For: METHODS FOR POLISHING SEMICONDUCTOR DEVICE STRUCTURES BY DIFFERENTIALLY APPLYING PRESSURE TO SUBSTRATES THAT CARRY THE SEMICONDUCTOR

**DEVICE STRUCTURES** 

Confirmation No.: 4590

Examiner: S. Macarthur

**Group Art Unit: 1792** 

Attorney Docket No.: 2269-4375.1US

VIA ELECTRONIC FILING October 6, 2008

## AMENDMENT ACCOMPANYING REQUEST FOR CONTINUED EXAMINATION

Mail Stop RCE Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

## Examiner:

This Amendment and the Request for Continued Examination (RCE) that it accompanies are being filed in response to a Decision of the Board of Patent Appeals and Interferences in the above-referenced application. The Decision was sent on August 4, 2008. As October 4, 2008, fell on a Saturday, this Amendment and the accompanying RCE should be considered to have been filed within two months of the date of the Decision.

A listing of claims, in which revisions to the claims are presented, begins on page 2 of this paper; and

Remarks start at page 7 of this paper.